Mechanisms of EUV Exposure: Internal Excitation and Electron Blur EUV Symposium – June 16, 2016

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- I. Introduction
- **II.** Internal Excitation
- **III. Experiment/Modelling of Electron Blur**



Goals and Motivation



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EUV Photons:

- Create Electrons → Can Cause Reactions
- Create Holes → Can Cause Reactions
- Deposit Energy \rightarrow Can Cause Reactions

What are the Mechanisms of These Reactions?

- For PAGs?
- For Metal-Containing Resists?

Understanding Should lead to Better Resists

Fundamental Reactions between e-, hv and Matter:



II. Internal Excitation



Internal Excitation of PAG by Passing Electron:

An electron could interact with a molecule to induce a HOMO/LUMO transition: analogous to photoexcitation.

One electron could "photolyze" several PAGs without being consumed.

These energy loss mechanisms are known in the EELS Literature for simple structures.*

*Ritsko et al. JCP 1978; JCP 1979; Vilar et al. JESRP 2009; Vilar et al. *Langmuir* 2003, Liehr Phys Rev B 1986.



Internal Excitation via Electron-Induced Fluorescence



Can we demonstrate this mechanism using fluorescent dyes?



Coumarin 6 Fluorescent Dye 5 SUNY POLYTECHNIC INSTITUTE

Experimental Schematic



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Fluorophores Studied



Best Performing Fluorophores



5000 eV E-Beam Fluorescence Maxima vs. Optical Fluorescence



III. Experiment/Modelling of Electron Blur



Thickness Loss was measured as a function of e- energy and dose.

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Thickness Loss of Open-Source Resist (OS2)



Comparison of Experiment with Monte Carlo Simulation using LESiS (Low-energy Electron Scattering in Solids)

LESiS is a fully stochastic simulation program designed originally by Leo Ocola.

- Cross-sections are calculated in real time.
- Monte Carlo is implemented in real time.

LESiS can simulate exposures by electrons or photons.

LESiS outputs data for each scattering event

- Energy
- Trajectory
- Identity, location, and orbital of the involved atom



LESiS Model Follows these Events:

= Core Electrons = Valence Electrons

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Energy Loss Events per e⁻ vs. Resist (OS2) Depth



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Thickness Loss Simulation (OS2, 700 eV)



Thickness Loss Simulation Results (OS2)



Thickness Loss Simulation Results (OS2)



Currently, LESiS does not adequately model Very Low-Energy Electrons.

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Threshold set to match 700 eV simulation and experimental data

Maybe these Energy Loss Events Don't Properly Model Chemical Reactions



Energy Loss Events per evs. Resist (OS2) Depth



Energy Loss Events per evs. Resist (OS2) Depth



Thickness Loss Simulation Results (OS2)



Thickness Loss Simulation Results (OS2)



A better model when 3 or 5 eV transitions are included.

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Threshold set to match 700 eV simulation and experimental data

Conclusions

Internal Excitation

- Demonstrated that secondary electrons can create excited states through internal excitation.
- Two dyes have significantly greater internal excitation quantum yields and very similar optical absorption maxima (450 nm/2.8 eV).
- However, the electron cross-sections for internal excitation by 80 eV electrons is low (~1%) for the best dyes. Key discoveries are required before this mechanism can be useful.

Thickness Loss/Electron Blur

- The best agreement between model and experiment is achieved when the reactivity of very low energy electrons (~3 eV) are included.
- This mechanism could improve sensitivity as a trade-off to electron blur.

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Appendix

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Open-Source Photoresist: OS2

For most of our work, we use an Open Source Chemically Amplified Resist, Called OS2.*



In some cases, we replace the PAG with equal weight (15 wt%) of these Photoacid Generators (PAGs):





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*Higgins, Brainard et al. JJAP *50*, 036504, **2011**



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